

IN THE CLAIMS:

Please CANCEL claim 1-8 without prejudice to or disclaimer of the recited subject matter.

Please ADD claims 9-15 as follows. For the Examiner's convenience, all claims currently pending in this application have been reproduced below:

1-8 (Canceled).

9. (New) An apparatus comprising:

a chamber;

a cooler to cool an inert gas to be supplied to said chamber;

a circulating path in which the inert gas flows through said chamber and said cooler;

a first path, connected to said circulating path at a first position downstream of an outlet port of said cooler and upstream of said chamber, to introduce air to said circulating path;

a second path, connected to said circulating path at a second position downstream of said chamber and upstream of an inlet port of said cooler, to exhaust gas in said chamber;

a first shut-off valve, arranged in said circulating path upstream of the first position and downstream of the outlet port of said cooler, to close before the introduction of the air; and

a second shut-off valve, arranged in said circulating path downstream of the second position and upstream of the inlet port of said cooler, to close, to prevent the air from flowing to said cooler.

10. (New) An apparatus according to claim 9, further comprising a filter arranged in said circulating path upstream of said first shut-off valve and downstream of said second shut-off valve.

11. (New) An apparatus according to claim 9, further comprising a blower, arranged in said circulating path upstream of the second position and downstream of said chamber, to cause one of the inert gas and the air to flow.

12. (New) An apparatus according to claim 9, further comprising a third valve, arranged in said first path, to open, to introduce the air to said circulating path.

13. (New) An apparatus according to claim 9, further comprising a fourth valve, arranged in said second path, to open, to exhaust gas in said circulating path.

14. (New) An exposure apparatus for transferring a pattern onto a substrate with exposure light, said apparatus comprising:

- a chamber having therein a space where the exposure light passes;
- a cooler to cool an inert gas to be supplied to said chamber;
- a circulating path in which the inert gas flows through said chamber and said cooler;
- a first path, connected to said circulating path at a first position downstream of an outlet port of said cooler and upstream of said chamber, to introduce air to said circulating path;

a second path, connected to said circulating path at a second position downstream of said chamber and upstream of an inlet port of said cooler, to exhaust gas in said chamber;

a first shut-off valve, arranged in said circulating path upstream of the first position and downstream of the outlet port of said cooler, to close before the introduction of the air; and

a second shut-off valve, arranged in said circulating path downstream of the second position and upstream of the inlet port of said cooler, to close, to prevent the air from flowing to said cooler.

15. (New) A method of manufacturing a device, said method comprising steps of:
transferring a pattern onto a substrate using an exposure apparatus as defined in claim 14;
developing the substrate onto which the pattern has been transferred; and
processing the developed substrate to manufacture the device.